

Docket No. GNE518US ARI.027

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Noboru MORITA, et al.

Serial No.: 10/766,921

Group Art Unit: 2818

Filing Date: January 30, 2004

Examiner: Nhu, David

For: METHOD OF FABRICATING SEMICONDUCTOR DEVICE USING PLASMA-
ENHANCED CVD

Honorable Commissioner of Patents
Alexandria, Virginia 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to examination on the merits, please amend the above-identified application as follows:

INTRODUCTORY COMMENTS

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Amendments to the Drawings begin on page 8 of this paper and include both an attached replacement sheet and annotated sheet showing a change.

Remarks begin on page 9 of this paper.